METHOD AND APPARATUS OF TESTING STRENGTH

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Applicant:

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- international:

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- european:

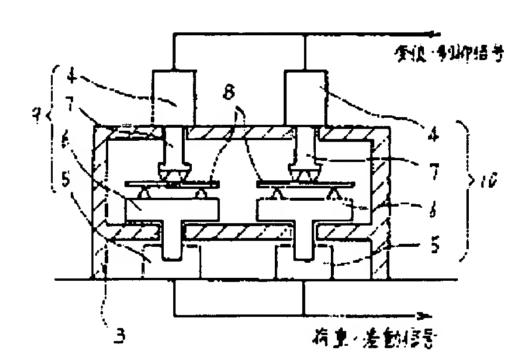
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Abstract of JP3122545

PURPOSE:To measure with less outer disturbances by providing a plurality of bend testers within the same container the temperature of which is adjustable, thereby to achieve tests simultaneously. CONSTITUTION: A bend tester 9 for testing a substrate and a bend tester 10 for testing a substrate with a thin film are set in a thermostat 3 under the circumstances of the same temperature. The displacement of each tester 9, 10 onto which a test piece 8 is placed by a feeding device 4 is measured by an electronic load cell 5. The Young's modulus of a thin film can be obtained from the differential signal of the load cell 5 and the deflection of the test piece 8 at a load point. Therefore, the measuring accuracy is improved and measuring time is shortened with the influences by the outer disturbances reduced.



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